

ECE520 – VLSI Design

Lecture 10: L-Edit Demo and Layout Techniques

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Review of Last Lecture

Overview of Design Rules

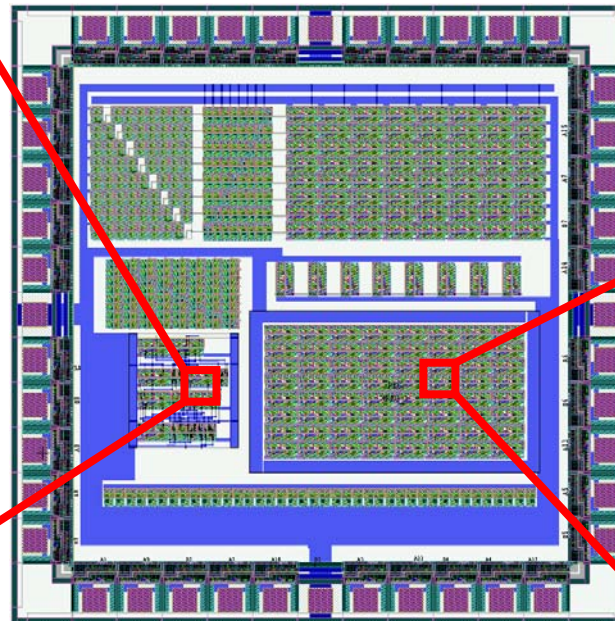
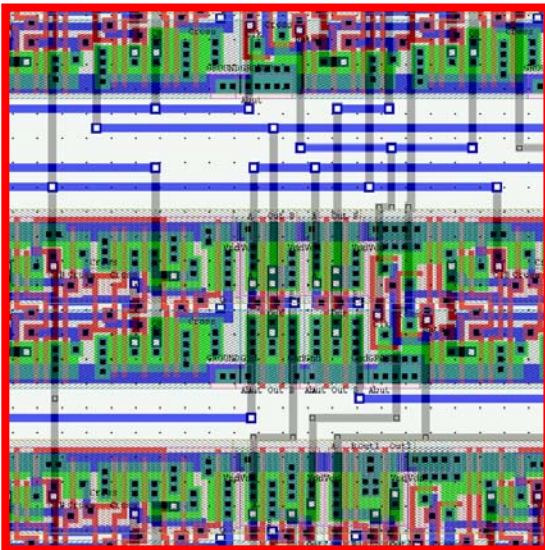
- What are design rules?
- Why have design rules?
- Typical design rules

Today's Lecture

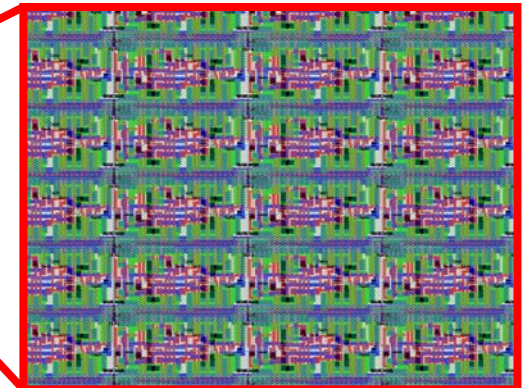
- ❑ **L-Edit Demo**
- ❑ **Layout Techniques**
 - Design for density
 - Design for performance
 - Design for reliability

An Example of Layout

**Control
(Random Logic)**



**Memory Cells
(Structural)**



Good Layout Characteristics

□ Density

- Cells pack together well
- Cells are routable—think about how they will fit together before starting!
- Start with paper diagram first

□ Performance

- Keep capacitances low (specially diffusion cap)
- Keep interconnects short

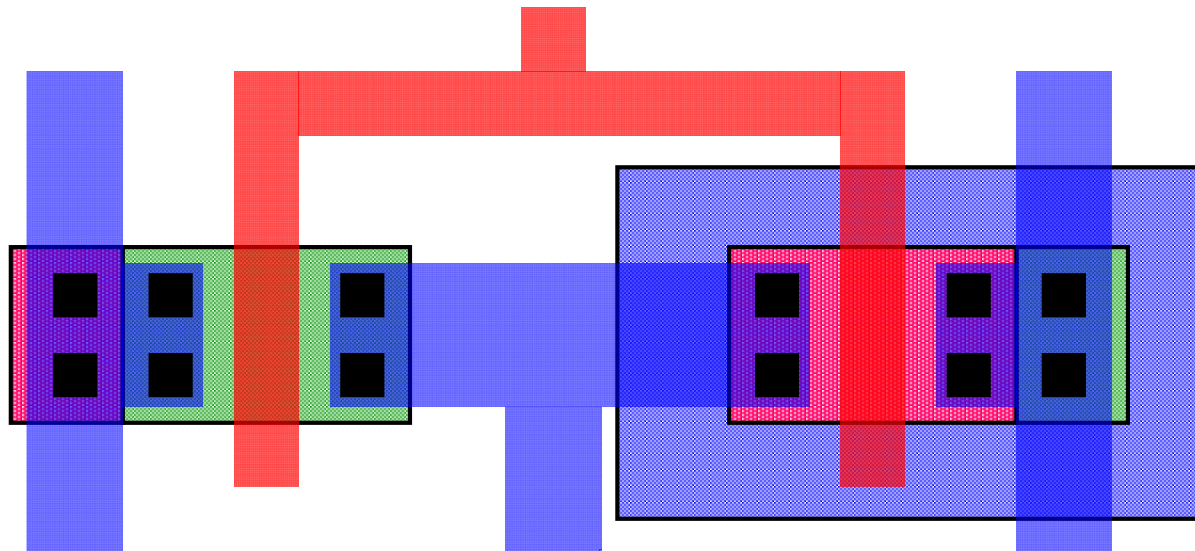
□ Reliability

- Poor layout can greatly affect the circuit reliability
- Use proper wire width for power rails (IR drop, electromigration)

□ Final Checks

- Layout must match the circuit being built (LVS)
- Layout must meet the manufacturing design rules (DRC)

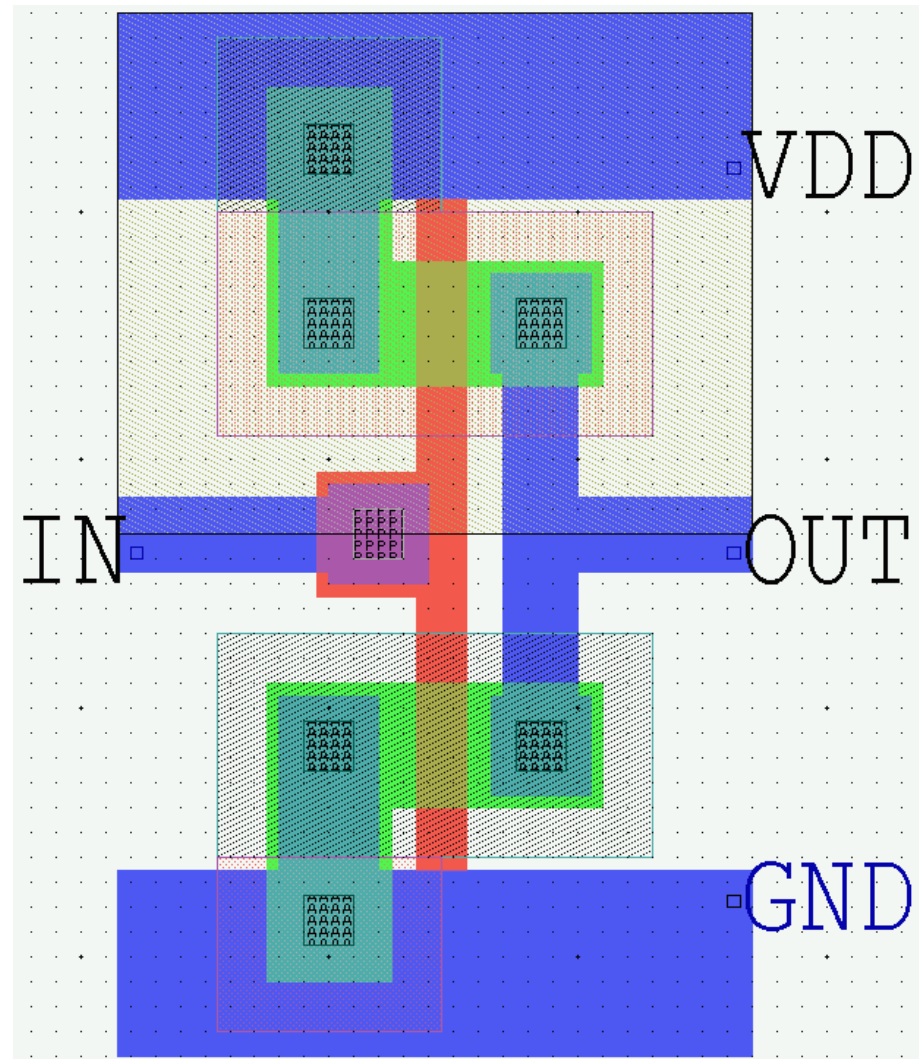
An Example of A Bad Layout



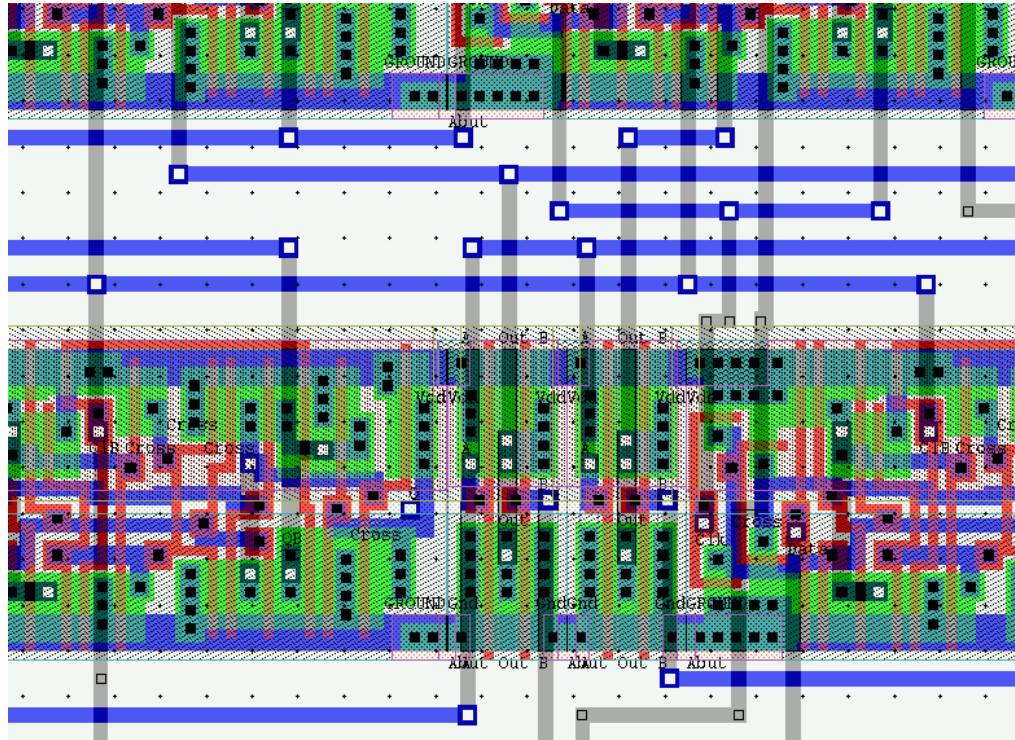
- Not dense
- Long poly route (large parasitic resistance)
- Narrow power rails

An Example of A Good Layout

- ❑ Very dense
- ❑ Short poly
- ❑ Wide power rails
- ❑ Both IN and OUT are in M1

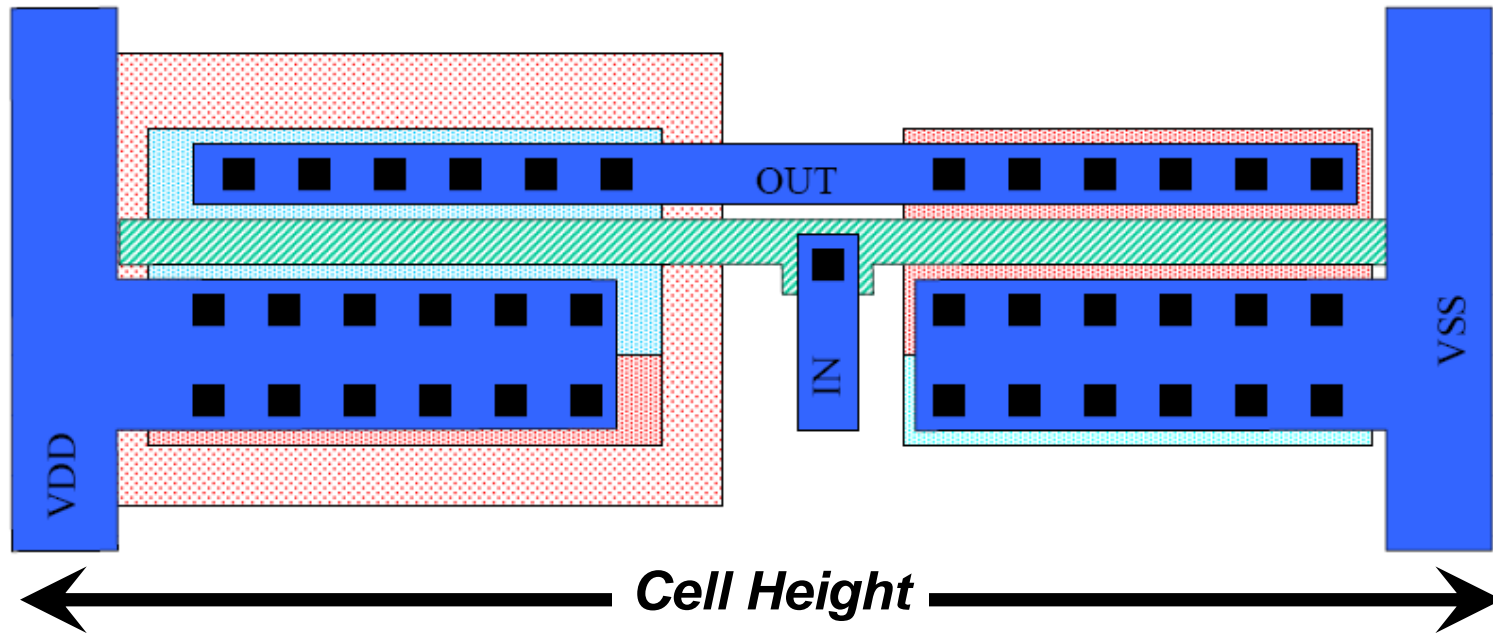


Channel Routing & Standard Cells



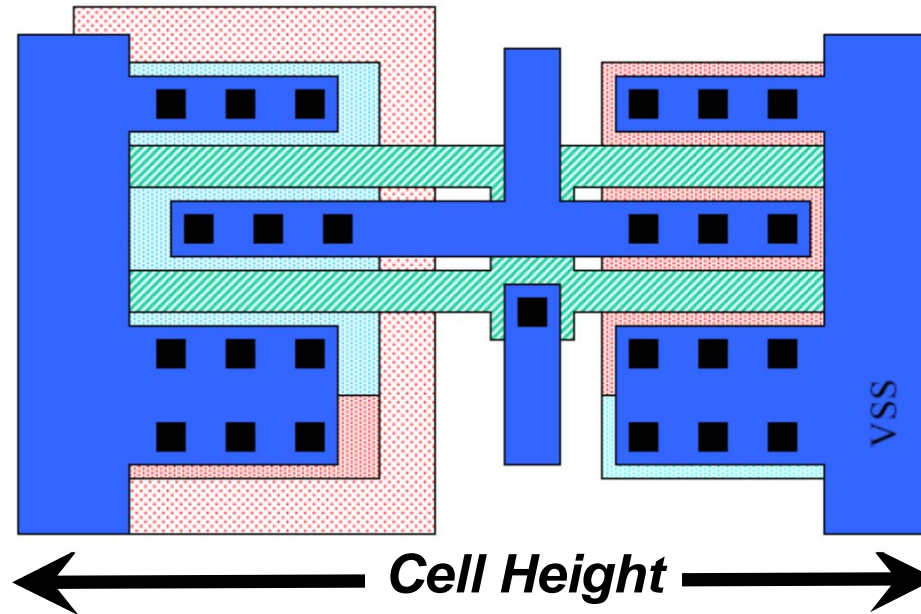
- All power and ground are connected nicely
 - This require that all cell height be the same for every cell
- M1 is used for horizontal routing in the channel
- M2 is used for vertical routing

Handling Large Device (Bad Layout)



- Long poly route (high resistance)
- Long source drain metal pickups (high resistance)
- Large cell height (mismatch with other cells)
- More component of diffusion cap than it needs to

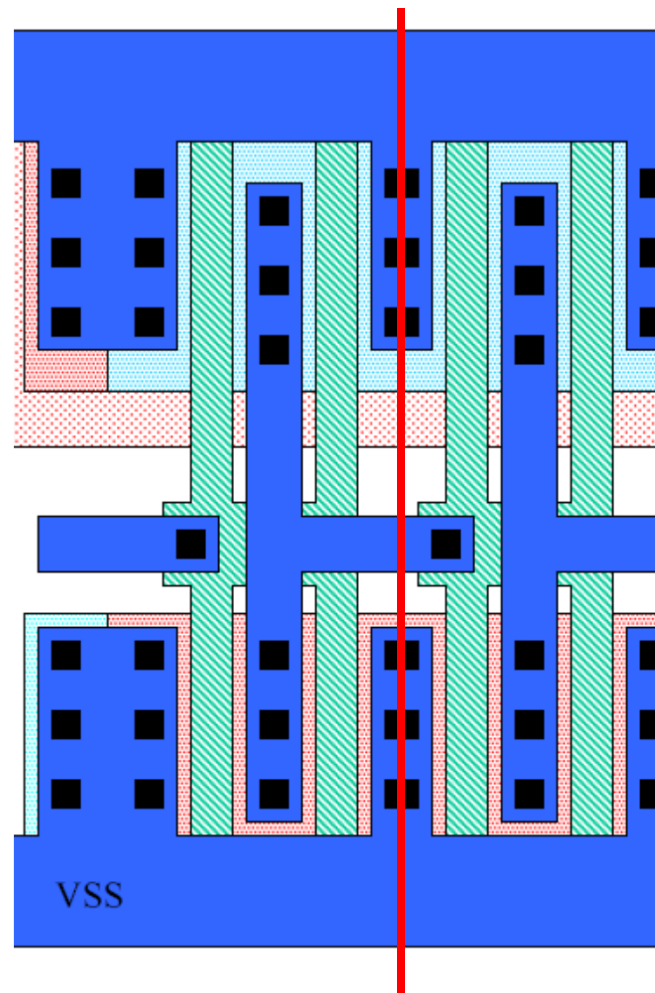
Handling Large Device (Good Layout)



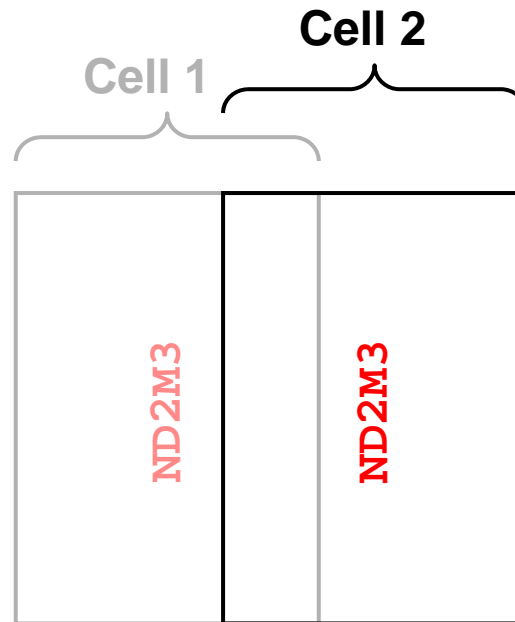
- ❑ The same drive strength (two folded transistor)
- ❑ Less diffusion capacitance (less P & A capacitance)
- ❑ Shorter poly route (lower resistance)
- ❑ Shorter source drain metal pickups (lower resistance)
- ❑ Smaller cell height (can be matched with other cells)

Advantage of Folding Transistors

- ❑ Less poly and metal length
 - Lower parasitic resistance
 - Lower parasitic capacitance
- ❑ Less Drain periphery and area
 - Less diffusion capacitance (less C_{out})
- ❑ Less cell aspect ratio
 - Better match with other cells
 - More compact and faster circuit
- ❑ Both ends are VDD or GND
 - Can easily share the ends with neighbors

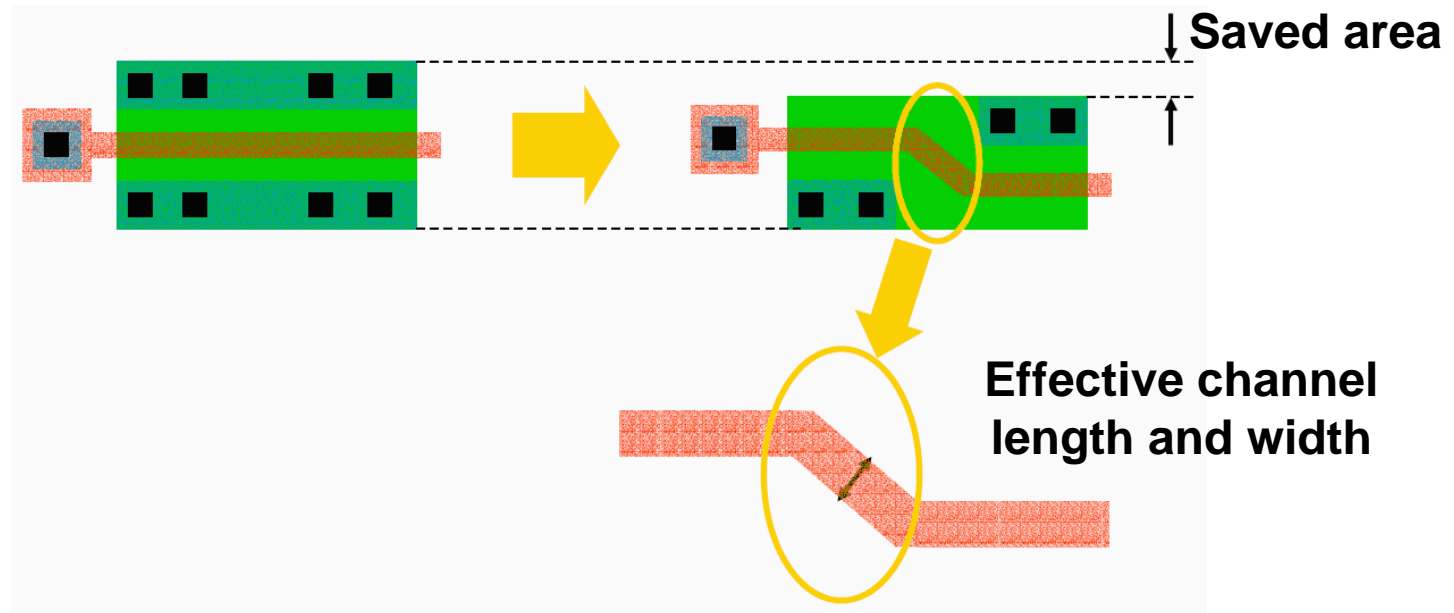


Overlapped Cells



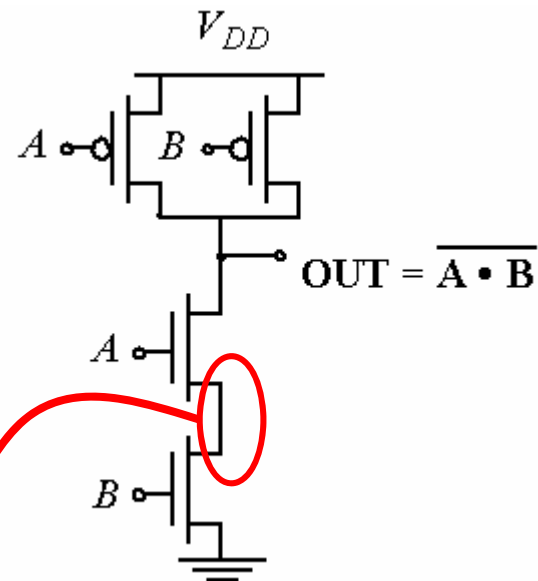
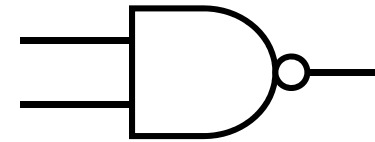
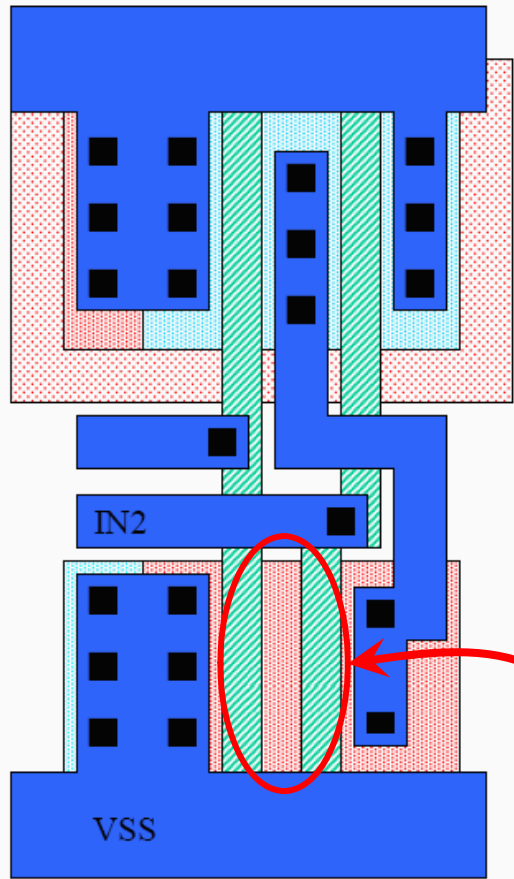
- ❑ **Our tools allow overlapping cells**
 - This allows a cell to be complete and still share with the adjacent cell for better density
- ❑ **This is why it is best to end cells on supplies**
 - It is not possible to do always tough!

Bent Gate



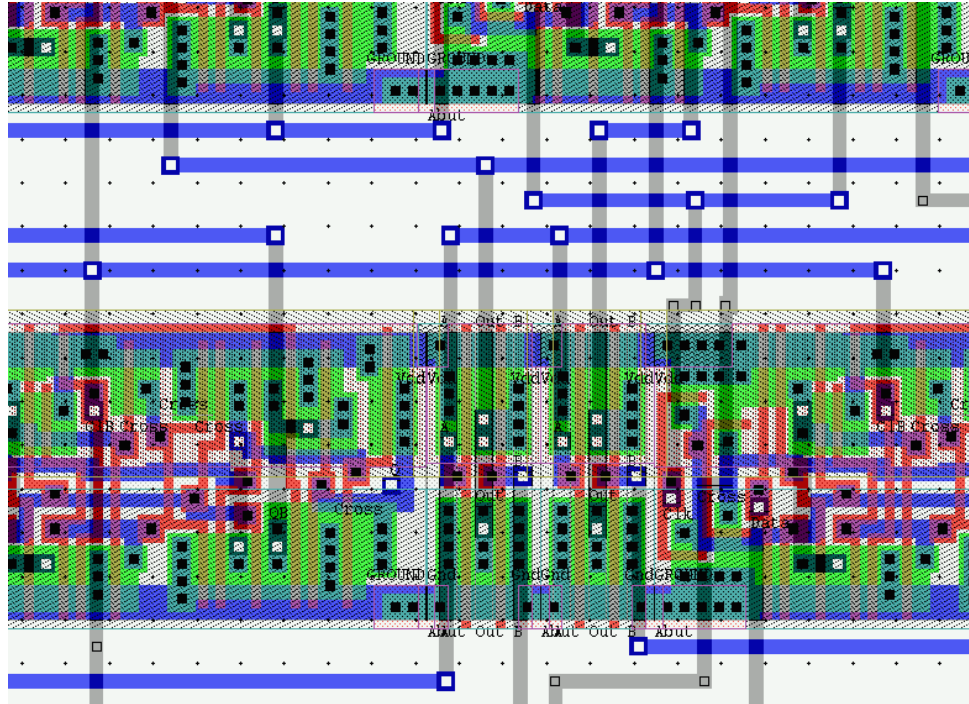
- If process permits, “bent gate” allows even denser layout
- Device modeling in this case requires more effort

Transistor Stacks



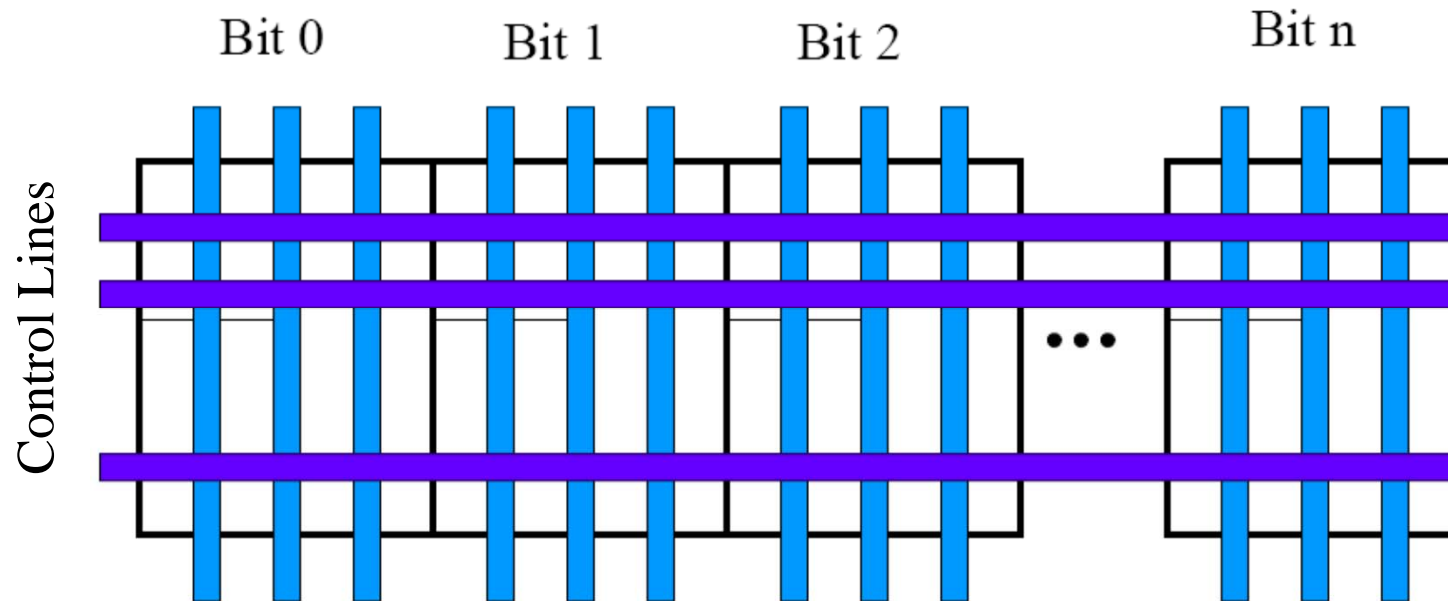
- ❑ When there is no other connection between two series device, they can be stacked
- ❑ Poly can be placed closer in stacked devices (because of DRC), which results in less diffusion capacitance

Random Logic Layout



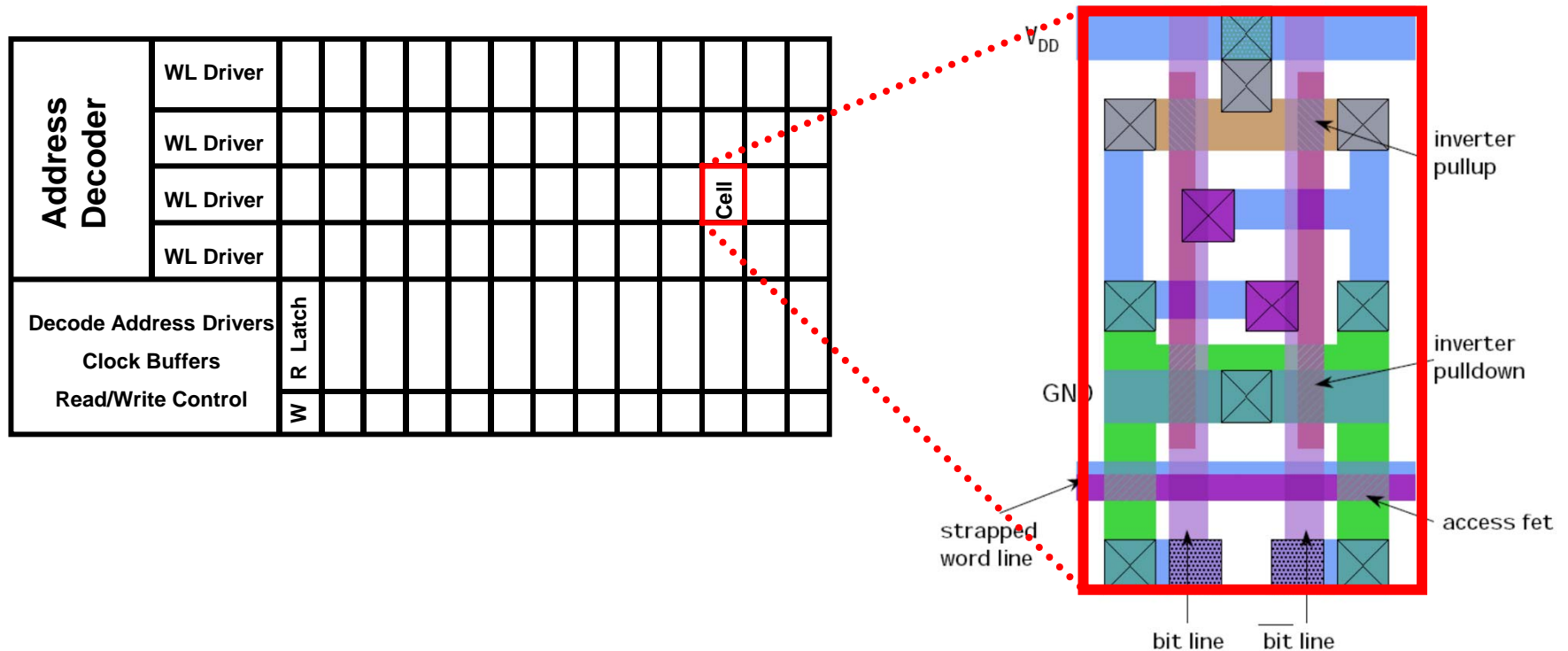
- ❑ Generally synthesized from an HDL description and automatically placed and routed (APR)
- ❑ Cells must be designed such that they line up nicely
- ❑ M1 is used for horizontal routing and M2 for vertical or vice versa

Data Path Layout



- ❑ All cells must lie on a fixed pitch
- ❑ Control lines cross and control all cells at once

SRAM Memory Layout



- All cells must lie on a fixed pitch (both directions)
- All lines “flow through” the cell and can be connected to adjacent cells by abutment
- The SRAM cells require no left right completion. Edge cells are required on top and bottom

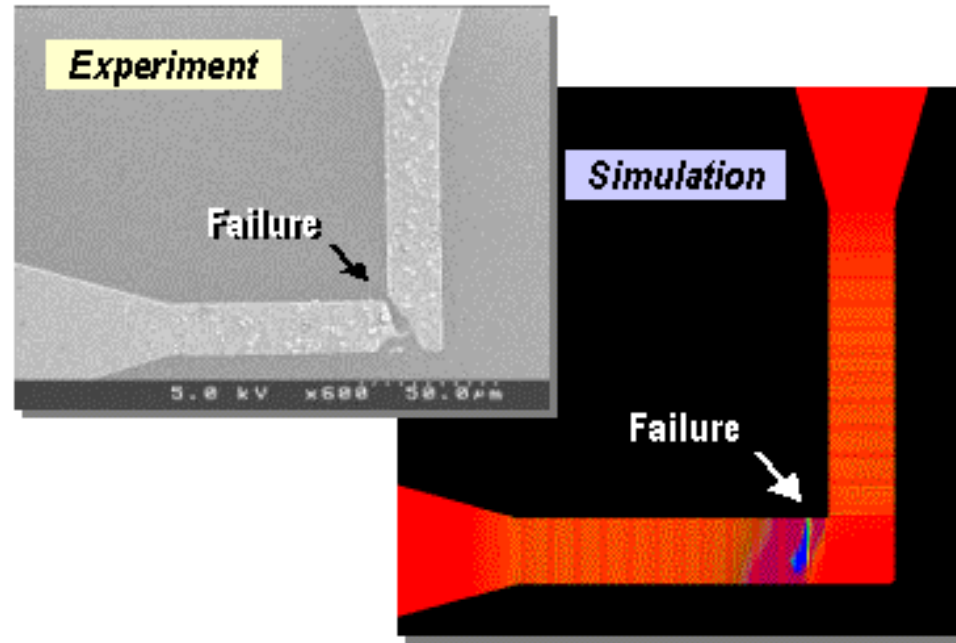
Layout Quality

- ❑ **Electromigration (EM) and self-heating (SH) are the key reliability issues determined by layout**
 - A quality layout will not limit the chip lifetime or speed

- ❑ **Electromigration: Metal atoms swept out of position by “electron wind”**
 - Only occurs on path where current flows in a single direction such as power supplies and between P and N devices
 - Depends on average current density
 - Highest at vias where the current crowds from the vias

- ❑ **Self Heating: Long term failure of metal due to local IR heating**
 - Occurs on wires with current flowing bidirectionally, eg, signal lines
 - Depends on I_{RMS}

Electromigration Modeling



- ❑ Using Physical models, we can predict where and when a failure can occur
- ❑ By shrinking wire dimensions, electromigration is becoming more important
- ❑ Advanced VLSI technology will require checking the layout for electromigration as we do for DRC

Electromigration and Self-Heat

❑ Electromigration

- Power Supply tracks
- The track between PMOS and NMOS
- Watch for “short circuit” current too

❑ Self-Heat

- Output node wire
- Can be large when C_L is large

- ❑ If the transistors are large, pre-determine the wire size and number of contacts and vias to prevent EM and SH

